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Seiko Seiki STP-H600, H1000

Technical Specifications

Item			STP-H600	STP-H1000
Flange size*1	Inlet port flange		ICF203/VG150/ISO160	ICF253/VG200/ISO200
	Outlet port flange		KF40	
Pumping speed	N_2	L/s	600	1000
	He	L/s	550	900
	N_2	L/s	500	800
Compression ratio	N_2		$>10^8$	
	He		10^4	
	N_2		10^3	
Ultimate pressure		Pa (Torr)	$10^{-7}(10^{-9})$ order (after baking)	
Maximum working pressure Pa (Torr)	When cooled water:		67 (0.5)	
	When cooled air:		5.3 (0.04)	
	When cooled natural air:		0.9 (0.007)	
	When TMS unit is used:		13(0.1)	
Allowable backing pressure Pa (Torr)	When cooled water: When TMS unit is used:		400 (3)	
	When cooled air: When cooled natural air:		267 (2)	
Rated speed		rpm	35,000	
Starting time		min	6	
Stopping time		min	6	
Vibration		μm O-P	<0.01 (at 35,000 rpm)	
Noise		dB	<50 (at 35,000 rpm)	
Baking temperature		°C	<120	
Lubricating oil			Not necessary	
Installation position			Free	
Cooling method*2			Water cooled, Air cooled, Natural air cooled	
Recommended auxiliary pump		L/min	240	
Mass*3		kg	31	32
Ambient temperature range		°C	0 to 40	
Storage temperature range		°C	- 25 to + 55	

Values shown in the above table are typical. They are not guaranteed.

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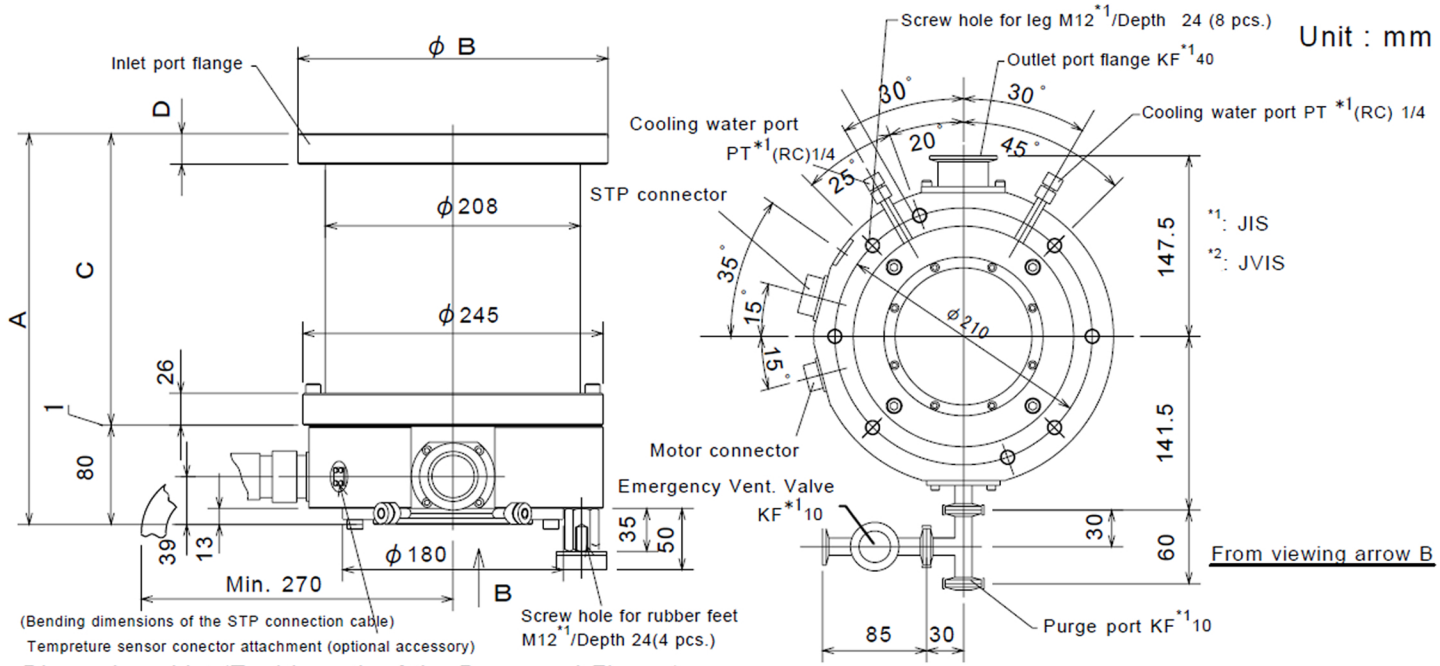
Dimensions



Dimensions List (Toal Length of the Pump and Flange)

Model	STP-H600 Series				STP-H1000 Series						
Flange	ICF*2203	VG*1150	ISO160	ISO160F	ICF253	VG200	ISO200	ISO200F	ISO250	ISO250F	ASA"6
A	339	339	339	339	319	319	319	319	319	319	339
B	ϕ203	ϕ235	ϕ180	ϕ225	ϕ253	ϕ300	ϕ240	ϕ285	ϕ290	ϕ335	ϕ279.4
C	258	258	258	258	238	238	238	238	238	238	258
D	22	14	12	16	25	18	12	16	15	16	12.4

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Seiko Seiki STP-H600, H1000

Features & Benefits

- oil free
- low vibration
- high reliability
- maintenance free
- increased life
- advanced controller design
- compact design
- small footprint
- advanced rotor technology
- installation in any orientation

Applications

- plasma etch • ECR etch • film deposition • sputtering • ion implantation source • beam line pumping • MBE • diffusion • photo resist stripping
- crystal / expitaxial growth • wafer inspection • load lock chambers

Recommended backing pump

- backing pump: QDP-40